

PROTECTION GATE VALVE SYSTEM

SPECIFICATIONS

TECHNOLOGY PHOTOVOLTAICS DISPLAY TECHNOLOGIES OLED/PLED NANOTECHNOLOGY AUTO LIGHTING
SYSTEMS NIGHT VISION AEROSPACE SEMICONDUCTOR SUPERCONDUCTOR OPTICAL & WEB COATING



GENERATION LASER TECHNOLOGY DATA STORAGE MASS SPECTROMETRY THIN FILM PHARMACEUTICALS
MOTOR VEHICLE LIGHTING SURFACE ANALYSIS R&D HIGH ENERGY PHYSICS HEAT TREATING NANOTECHNOLOGY



Protect Your Investment

► New! Protection Valve System

FEATURES

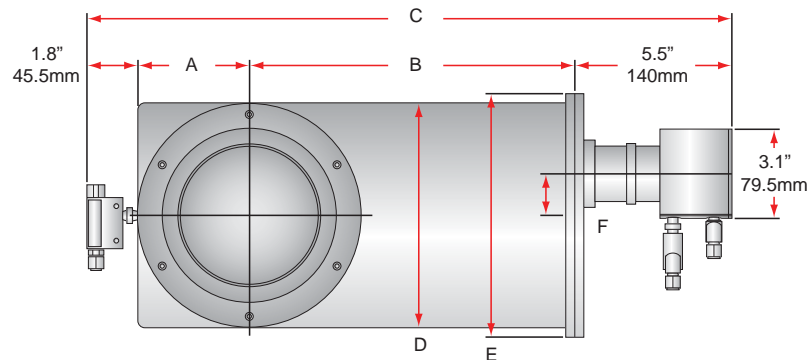
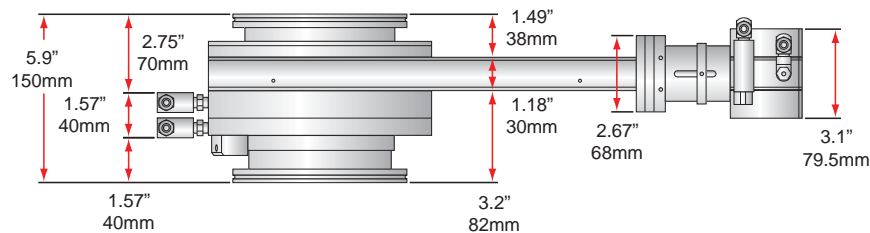
Features:

- Fast pneumatic actuation—closes in <0.3 seconds
- Patented shielding mechanism for low particulate generation
- Bellows-sealed actuator
- Long cycle life under adverse process conditions
- Low shock/motion during open/close cycling
- Local/remote control with status LCD display
- Easy routine maintenance
- 1, 2, 3, or 4 channel control options

APPLICATIONS

For vacuum pump or chamber isolation in demanding processes:

- Plasma etching, cleaning, and desmearing
- All CVD processes (including MO, PE, HDP, LP, and AP)
- Sputter deposition and e-beam/thermal evaporation
- Nanotechnology processes with high particulate levels
- Thin film photovoltaic panels



Flange Size	Dimensions						Weight (kg.)	Part No.
	A	B	C	D	E	F		
100 ISO-K	3.3" (84mm)	9.5" (242mm)	20.1" (512mm)	6.6" (168mm)	7.3" (186mm)	1.2" (31.5mm)	15	GVP0400IK
160 ISO-K	4.4" (112mm)	13.3" (337mm)	23.2" (589mm)	8.8" (224mm)	9.4" (240mm)	1.9" (48mm)	21	GVP0600IK

of In-Process Products.



SPECIFICATIONS

Specifications:

- Pressure Range: 1×10^{-7} mbar – 1 atm
- Leak Rate: $< 6 \times 10^{-8}$ mbar.L/sec
- Air Pressure: 60 – 100 PSI (4.1 – 6.9 bar)
- Differential Pressure:
 - Gate: 1 bar in either direction
 - At opening: ≤ 30 mbar in either direction
- Material:
 - Body: 304 SS
 - Bellows: 316L SS
 - Actuator: AI-6061
 - Seals: Viton[®]
- Temperature:
 - Body: $< 150^{\circ}\text{C}$
 - Actuator: $< 60^{\circ}\text{C}$

GLOBAL VACUUM PRODUCT LINES

VACUUM MART™ DIVISION

Vacuum Valves & Hardware

- Flanges, Components, & Fasteners
- Gate & Angle Valves
- OFHC Copper Gaskets
- Bellows, Tubing, & Seals
- Semiconductor, PV, & FPD Process Valves

Feedthroughs

- Power & High Voltage
- Viewports (Optical Feedthrough)
- Coaxial & Instrumentation
- Thermocouple
- Ferro-Magnetic Fluid Rotary Drives
- USB

Vacuum Pumps & Accessories

- New & Remanufactured
- Rotary Vane & Piston
- Scroll & Diaphragm
- Screw & Roots Blowers
- Turbo & Diffusion
- Cryogenic & Ion
- Traps & Filters
- Complete Offering of Pump Repair Services

Vacuum Fluids

- Full Line of Mechanical Pump Oils
- Fomblin® PFPE - Inert PFPE
- Galden® PFPE - Heat Transfer Fluid
- Vacuum Greases, Sealants, & Solvents
- Pump Oil with R/O Additives
- Silicon Diffusion Pump Oils
- Pump Oil Recycling

Pressure Measurement

- Analog & Digital Active Gauges
- Pressure Indicators & Controllers
- Wide-Range Gauges
- Multi-Gauge Controllers
- Replacement Gauge Tubes
- MKS Baratrons®

Sample Manipulation & Motion

- Rotary & Linear Motion
- Linear Positioners
- Wobble Sticks & Port Aligners
- XYZ Manipulators
- Multi-Axis Manipulators
- Sample Transfer Probes
- Sample Heating & Rotation
- Motion Control
- Sample Distribution Center

Vacuum Services

- Full Line Pump Repair/Rebuild Services
- Pump Oil Recycling
- Technical Information
- Technical Consulting
- Decontamination
- Magnetron Cathode Service
- Contract Manufacturing

PROCESS EQUIPMENT™ DIVISION

Deposition Sources

- Torus® Magnetron Sputtering Sources
- Electron Beam Evaporation
- Organic Material Sources
- Electron Beam Sources
- Ion Sources
- Thermal Evaporation Sources

Process Instrumentation

- Film Thickness
- Mass Flow Controllers
- RF & DC Power Supplies
- Pulsed DC Power Supplies
- Power Supplies for Evaporation

System Components & Custom Engineered Solutions

- Turnkey & Partial Build Solutions
- Comprehensive Engineering Design Support
- Chambers, Frames, & Mounting Structures
- High Temperature & Bakeout Heater Assemblies
- Heater Power Supplies
- Substrate Load Locks & Transfer Vessels

Vacuum Systems

- Thin Film Deposition Systems
- Cluster Tools
- Box Coaters
- General PVD Systems
- Computerized Systems
- Combinatorial Systems
- Organic Material Deposition Systems
- R&D Sputter Tools
- Vacuum Furnaces & Ovens
- Atomic Layer Deposition (ALD)
- Drum Coaters
- In-line & Linear Systems
- R2R Systems

MATERIALS™ DIVISION

Deposition Materials

- Sputtering Targets
- Precious Metals & Reclaim
- Evaporation Pieces
- Thermal Evaporation Sources
- E-Beam Crucible Liners
- Bonding Service
- Backing Plates
- Ceramic Materials Manufacturing (CMM)

MANUFACTURING™ DIVISION

Vacuum Chambers & Components

- Standard SS Cylindrical, D-Shaped, Spherical, & Box Chambers
- Standard Pyrex® Glass Bell Jars & Cylinders
- Standard Building Blocks to Customize Your System
- Custom Chambers
- Array of Finishes & Materials
- Easily Build Your Own Chamber with the Custom Chamber Configurator On-line

Manufacturing & Fabrication

- State-of-the-Art CNC Machining
- Mechanical, Manufacturing, & Industrial Engineering
- Computer Based Scheduling & Routing
- CAD, CAM, & FEA Software
- Coordinate Measuring Machine Inspection (CMM)
- UHV Compatible Cleaning Process

We have a network of representatives around the world ready to service the international vacuum community.

Visit our website to find the representative nearest you, or contact our International Sales Department.

www.lesker.com/locations

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